

Attorney Docket No. 081468-0306001
Client Reference: P-0358.010-US

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: **KONSTANTIN NIKOLAEVITCH KOSHELEV, VADIM YEVGENYEVICH BANINE, VLADIMIR VITAL'EVITCH IVANOV, ERIK RENE KIEFT, ERIK ROELOF LOOPSTRA, LUCAS H. J. STEVENS, YURII VICTOROVITCH SIDELKOV, VSEVOLOD GRIGOREVITCH KOLOSHNIKOV, VLADIMIR MIHAILOVITCH KRIVTSUN, ROBERT RAFILEVITCH GAYAZOV, and OLAV W. V. FRIJNS**

Application No.: Not Yet Assigned
Filed: September 17, 2003

Confirmation No: Not Yet Assigned
Group No.: Not Yet Assigned
Examiner Not Yet Assigned

For: **RADIATION SOURCE, LITHOGRAPHIC APPARATUS AND DEVICE MANUFACTURING METHOD**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

APPLICATION DATA SHEET
37 C.F.R. § 1.76

BIBLIOGRAPHIC DATA

1. Applicant information

First applicant: **KONSTANTIN NIKOLAEVITCH KOSHELEV**
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2. Correspondence information

Correspondence for this application should be addressed as follows:

Customer No.: 00909

3. Application information

Title of Invention: RADIATION SOURCE, LITHOGRAPHIC APPARATUS AND DEVICE
MANUFACTURING METHOD

Docket number assigned to this application: 081468-0306001

Suggested Classification: Class:
Subclass:
Technology Center to which subject matter is assigned:

Total number of drawing sheets: 14

Type of application:

Utility

Application is to be published. Suggested drawing figure for publication:

Secrecy order under § 5.2:

This application does not disclose subject matter of an application which is under a secrecy order pursuant to § 5.2.

4. Representative information

The following have a power of attorney or authorization of agent in this application:

Customer No.: 00909

5. Foreign priority information

Foreign priority is claimed for this application as follows:

Country: European
Application No.: 02256486.8
Filing Date: September 19, 2002
Status:

Country: European
Application No.: 02256907.3
Filing Date: October 3, 2002
Status:

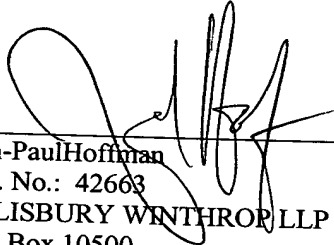
6. Assignee information

The assignee(s) of this application is/are:

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Extent of interest of assignee in application:

Date: Sept. 17, 2003



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